

# Akshay Gowda

## List of Publications by Year in descending order

Source: <https://exaly.com/author-pdf/9065789/publications.pdf>

Version: 2024-02-01

9

papers

99

citations

1684129

5

h-index

1872665

6

g-index

9

all docs

9

docs citations

9

times ranked

58

citing authors

#	ARTICLE	IF	CITATIONS
1	3D trajectories and diffusion of single ceria particles near a glass surface and their removal. Journal of Materials Research, 2021, 36, 258-267.	2.6	2
2	Real-Time Visualization of the Cleaning of Ceria Particles from Silicon Dioxide Films Using PVA Brush Scrubbing. ECS Journal of Solid State Science and Technology, 2021, 10, 084004.	1.8	5
3	3D trajectories and diffusion of single ceria particles near a glass surface and their removal. Journal of Materials Research, 2021, 36, 1-10.	2.6	0
4	A Novel Method to Quantify Conditioner-to-Conditioner Variation and Predict Conditioner Lifetime and Process Failure Mode in Chemical Mechanical Planarization (CMP) Environment. IEEE Transactions on Semiconductor Manufacturing, 2020, 33, 614-621.	1.7	0
5	Cleaning Solutions for Removal of $\sim 30$ nm Ceria Particles from Proline and Citric Acid Containing Slurries Deposited on Silicon Dioxide and Silicon Nitride Surfaces. ECS Journal of Solid State Science and Technology, 2020, 9, 044013.	1.8	20
6	Selective Polishing of Amorphous Silicon Carbonitride (a-SiCN) Films Over Silicon Dioxide and Silicon Nitride Films for Hardmask Applications. ECS Journal of Solid State Science and Technology, 2020, 9, 034004.	1.8	0
7	Trajectories, diffusion, and interactions of single ceria particles on a glass surface observed by evanescent wave microscopy. Journal of Materials Research, 2020, 35, 321-331.	2.6	8
8	Reactive Liquids for Non-Prestonian Chemical Mechanical Polishing of Polysilicon Films. ECS Journal of Solid State Science and Technology, 2019, 8, P3040-P3046.	1.8	6
9	Almost Complete Removal of Ceria Particles Down to 10 nm Size from Silicon Dioxide Surfaces. ECS Journal of Solid State Science and Technology, 2018, 7, P243-P252.	1.8	58